

REMARKS/ARGUMENTS

In the Advisory Action of July 12, 2004, the Examiner concluded that the amendment filed on June 23, 2004, does not place the application in condition for allowance because "claim 1 does not require that the plasma being [sic] continuously on." What the Examiner seemed to say is that the term "idle condition plasma" must be read broadly to include a condition in which the plasma has been entirely turned off.

To overcome this problem Claim 1 has been amended to recite that the "method compris[es] creating a plasma in the reaction chamber and *performing all of the following in the sequence indicated while maintaining said plasma in said reaction chamber*" (emphasis added) This limitation is clearly supported, for example, at page 3, lines 13-19, and at page 6, lines 13-14, where it is stated that the "plasma conditions continue to be maintained while the cooled wafer is transferred out of the chamber."

For the reasons stated in the June 23, 2004, amendment, which are incorporated herein by reference, Kwan et al. in view of Rice et al. do not teach or suggest this limitation.

Claims 21 and 22 have been canceled in response to the Examiner's restriction requirement. Claims 25 and 26 have been added, leaving Claims 1-20 and 23-26 pending.

Should the Examiner wish to discuss this case, the Examiner is invited to call the undersigned at (408) 982-8200, ext. 1.

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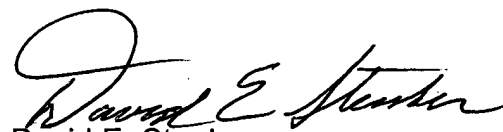


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8/23/04

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